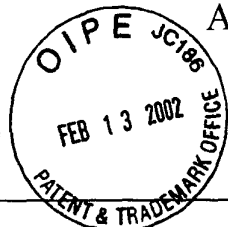


INFORMATION DISCLOSURE  
CITATION IN AN  
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APPLICANT  
**Roger S. SILLMON, et al.**

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**2812**

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EXAMINER

AKC

DATE CONSIDERED

7/23/03